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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/532,856	06/07/2005	Roland Anthony Tacke	1304.066USU	1935

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EXAMINER

VERDERAME, ANNA L

ART UNIT	PAPER NUMBER
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1795

MAIL DATE	DELIVERY MODE
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12/28/2007

PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Office Action Summary	Application No. 10/532,856	Applicant(s) TACKEN ET AL.	
	Examiner Anna L. Verderame	Art Unit 1795	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 27 April 2005.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-14 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1-14 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 27 April 2005 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☒ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. _____.
 3. ☒ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|---|---|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____ |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | 5) <input type="checkbox"/> Notice of Informal Patent Application |
| 3) <input checked="" type="checkbox"/> Information Disclosure Statement(s) (PTO/SB/08)
Paper No(s)/Mail Date <u>04/27/2005</u> | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Claim Objections

1. Claim 5 is objected to because of the following informalities: In line 5, "photoresit" should be photoresist. Appropriate correction is required.

Claim Rejections - 35 USC § 112

2. The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

3. The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

4. Claim 10 recites the limitation "exposed parts" in line 3. There is insufficient antecedent basis for this limitation in the claim. Line 2 of claim 10 recites a treatment but not an exposure. The examiner suggests changing "exposed" to "treated".

Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(a) the invention was known or used by others in this country, or patented or described in a printed publication in this or a foreign country, before the invention thereof by the applicant for a patent.

2. Claims 1-6 and 10-14 are rejected under 35 U.S.C. 102(a) as being anticipated by Hendriks et al. WO 02/09103.

Hendriks et al. teaches a method for manufacturing a substrate for use in a

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stamper manufacturing process comprising the following steps; a) coating a crosslinkable chemical composition on a substrate; b) subjecting the undercoating applied in step a to a) to a crosslinking reaction; and c) applying a top coating of photosensitive material to the undercoating that has been crosslinked in step b), wherein the thickness of the crosslinked undercoating of step b) is selected so that the maximum energy intensity during the exposure step of the stamper manufacturing process occurs at the desired post height of the top coating that is to be developed (page 4 lines 10-19). In particular step b) is carried out by using a heat treatment, in particular at a temperature ranging from 150-250°C. Such a temperature range will result in three-dimensional cross-linking of the polymer chains of the chemical composition provided in step a). In another embodiment step b) is carried out using an exposure step, in particular in the wavelength range of 200-300 nm (UV-light). The exposure time is in particular 5-180 seconds, whereby the exposure step is carried out in particular while rotating and/or heating the substrate. Since the crosslinkable composition has undergone a crosslinking reaction in step b), the thus crosslinked composition is not soluble, or only to a small degree, in the solvent that is used in the photosensitive material that has been provided in step c). In step d) solvent is removed from the top coat by heating the layer at a temperature of maximally 130°C so as to assure that no further cross-linking of the lower layer occurs (5/9-30). Further, the reference discloses that it is desirable to subject the substrate to a preparation step prior to carrying out step a), which comprises the cleaning of the substrate and possibly the application of an adhesion layer for the crosslinkable composition that is applied in

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step a). The adhesion layer, on account of its thickness can only be considered a “**monolayer**”(page 2 line 20). The present substrate is in particular suitable for use in a method for manufacturing a stamper, which stamper is placed in the mould of an injection moulding machine for mass producing CD replicas(page 6/line 30-page 7/line 1). The limitation of claims 12-13 are disclosed at (page 2 lines 8-15).

Claim Rejections - 35 USC § 103

3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

4. Claim 7 is rejected under 35 U.S.C. 103(a) as being unpatentable over Hendriks et al. WO 02/09103 in view of Peterson et al. 5,702,767.

Hendriks et al. WO 02/09103 teaches the application of an adhesion layer, but does not teach the limitations recited in claim 7.

Peterson teaches a method for providing an inorganic substrate having improved adherence for polymeric films(abstract). In examples 1-3 Peterson applies HMDS to a silicon wafer(11/35-55). Practical application of the invention is disclosed at (11/15-33). Suitable substrates are taught at (8/19-33). Disclosure of TMSDEA and HMDS as priming agents is found at (2/59-63).

It would have been obvious to one of ordinary skill in the art to modify the

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method for manufacturing a substrate for use in a stamper manufacturing process taught by Hendriks et al. by forming an adhesion layer on the substrate prior to step a.) wherein the adhesion layer is HMDS **monolayer** based on the disclosure to form an adhesion layer in Hendriks et al. and based on the example of Peterson et al. found at (11/25-55) and with the reasonable expectation of forming a substrate having an improved adherence for polymeric films as disclosed in the abstract of Peterson et al.

5. Claims 8-9 are rejected under 35 U.S.C. 103(a) as being unpatentable over Hendriks et al. WO 02/09103 in view of Peterson et al. 5,702,767 as presented above, and further in view of Thompson 6,361,921.

Hendriks et al. WO 02/09103 in view of Peterson et al. 5,702,767 as presented above does not teach rinsing the adhesive layer directly upon application for a relatively short amount of time. The references also do not teach a rinsing time of 5 seconds at maximum as recited in claim 9.

Thompson teaches a comparative example in which HMDS is coated on glass slides(10/50-60). The method usually comprises formation of a primer on a cleaned substrate of silicon, nickel, etc. Thompson teaches washing the surface with an effective amount of the priming composition. Further, Thompson teaches optionally rinsing the surface of the substrate with an aqueous solution(water) sufficient to remove contaminants and leave a **thin film** of priming composition on the cleaned surface. A photoresist is then formed on the priming composition layer(3/12-30).

Formation of an adhesive monolayer is clearly articulated by Hendriks et al. Further, rinsing to remove contaminants immediately after application of the adhesive

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layer is articulated by Thompson. The rinsing time needed to achieve the adhesive monolayer depends upon the thickness of the originally applied adhesive layer. If a thick adhesive layer is applied a longer rinsing time can be employed. If a thinner layer is applied a shorter rinsing time is necessary. Also, there is a minimum amount of rinsing time necessary to achieve any sort of result including removal of contaminants. Therefore, it would have been obvious to one of ordinary skill in the art to optimize the rinsing time in order to achieve the desired adhesive monolayer.

The experimental modification of this prior art in order to ascertain optimum operating conditions fails to render applicants' claims patentable in absence of unexpected results. In re Aller, 105 USPQ 233. One of ordinary skill in the art would have been motivated to adjust the rinsing time in order to achieve the desired adhesive monolayer. A prima facie case of obviousness may be rebutted, however, where the results of the optimizing variable, which is known to be result-effective (longer rinsing times lead to the removal of more material), are unexpectedly good. In re Boesch and Slaney, 205 USPQ 215.

It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the process taught by the combination of Hendriks et al. WO 02/09103 in view of Peterson et al. 5,702,767, by rinsing the HMDS layer immediately after application in order to remove contaminants based on the teachings of Thompson, and with the reasonable expectation of forming an adhesive monolayer which is free of contaminants.

Conclusion

6. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.

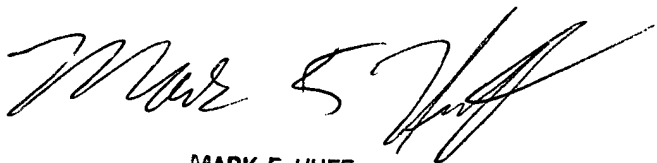
-Brochot et al. US5,093,153- teaches organosilicon coating thickness of between 20-200 nm(9/21). Also teaches organosilicon monomers(5/20-36).

7. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Anna L. Verderame whose telephone number is (571)272-6420. The examiner can normally be reached on M-F 8A-4:30P.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Mark Huff can be reached on (571)272-1385. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

ALV



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